

PTO-1449

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**Information Disclosure Citation
In an Application**

Application No.

10/849,192

Docket Number

074036.0127

Applicant(s)

Mohammed N. Islam et al.

Group Art Unit

Filing Date

2872

August 27, 2003

U.S. PATENT DOCUMENTS

	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A						
B						
C						
D						
E						
F						
G						
H						
I						
J						
K						
L						
M						

FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
N						YES
O						NO
P						

NON-PATENT DOCUMENTS

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
Q	Y. Chen, et al., "Modeling and Control of Nanomirrors for EUV Maskless Lithography," Technical Proc. Int. Conf. Modeling and Simulations of Microsystems, San Diego, CA, 3 pages	March 2000
R	W.R. Wlezniewski et al., "Mechanical Light Modulator Fabricated on a Silicon Chip using Simox Technology," pp. 1027-1030	December 1996
S		
T		
U		
V		

EXAMINER

J. Alyngula

DATE CONSIDERED

4 AUGUST 2004

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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**Information Disclosure Citation
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Application No.

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A	4,728,185	03/01/1988	Thomas	353	122	02/20/1987
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C	5,287,652	01/11/1994	Urbanus et al.	358	160	03/23/1993
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U	—	—	—	—	—	YES NO

NON-PATENT DOCUMENTS

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
V	—	—
W	—	—

EXAMINER*John Gulec***DATE CONSIDERED***4 AUGUST 2004*

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